Unofficial Proposed Avendment

U.S. Patent Application No.: 10/665,572

3/3/2006

CLAIM SHEET

1. (Cancelled)

- 2. (Currently Amended) A composition for forming a piezoelectric film

 The method according to claim 1, claim 7, wherein said metallic compound is selected

 from the group consisting of organometallic alkoxides, organometallic complexes, metal

 organic salts, and metal hydroxides.
- 3. (Currently Amended) A composition for forming a piezoelectric film

 The method according to elaim 1, claim 7, wherein the content of hafnium contained in said composition is 2,000 ppm or less.
 - 4. (Cancelled)
 - 5. (Cancelled)
- 6. (Currently Amended) A piezoelectric element The method according to elaim 5, claim 7, wherein the content of hafnium contained in said piezoelectric film held between the lower electrode and the upper electrode is 3,000 ppm or less.
- 7. (Currently Amended) An A method for producing a piezoelectric film for an ink jet recording head, said ink jet recording head comprising:

Unofficial Proposed Amendment

a pressure chamber communicating with an ink discharge port, port;

a diaphragm provided in correspondence with said pressure chamber,

chamber; and

the \underline{a} piezoelectric element of claim 5 provided in correspondence with the diaphragm,

wherein an ink in said pressure chamber is discharged through said ink discharge port by a change of volume in said pressure chamber caused by the piezoelectric element,

wherein the piezoelectric element comprises the piezoelectric film, and the piezoelectric film is held between a lower electrode and an upper electrode, and wherein said method comprises the steps of:

coating a substrate with a composition for forming the piezoelectric film, to

form a coating film, said composition containing a dispersoid obtained from a metallic

compound, and the content of hafnium in said composition being 3,000 ppm or less;

drying the coating film; and

sintering the dried coating film to obtain the piezoelectric film.

CA_MAIN 110064v1